

Notice of References Cited

Application/Control No.

10/588,833

Applicant(s)/Patent Under
Reexamination
LIEBER ET AL.

Examiner

DAREN WOLVERTON

Art Unit

2813

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,998,333	02-2006	Chen et al.	438/607
*	B	US-6,897,098	05-2005	Hareland et al.	438/128
	C	US-			
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	I	US-			
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	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

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	V	Zhang, Z. et al. "Electrically robust ultralong nanowires of NiSi, Ni ₂ Si, and Ni ₃ Si ₂ ", 24 January 2006, Applied Physics Letters 88, 043104 (2006)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.